

Under the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it contains a valid OMB control number.

Substitute for form 1449/PTO

**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

(Use as many sheets as necessary)

Complete if Known

| | |
|------------------------|-------------------|
| Application Number | 10/666,147 |
| Filing Date | 18 September 2003 |
| First Named Inventor | Deb et al. |
| Art Unit | 2858 |
| Examiner Name | Not Yet Assigned |
| Attorney Docket Number | DB001039-001 |

Sheet 1 of 3

NON PATENT LITERATURE DOCUMENTS

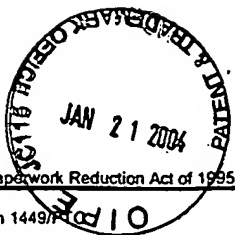
| Examiner Initials* | Cite No. ¹ | Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published. | T ² |
|--------------------|-----------------------|---|----------------|
| HR | 1 | A. KOUREPENIS, J. BORENSTEIN, J. CONNELLY, R. ELLIOTT, P. WARD, and M. WEINBERG, "Performance of MEMS Inertial Sensors," Position Location and Navigation Symposium, pp. 1-8, April 1998. | |
| HR | 1 | R. LAL, P.R. APTE, N.K. BHAT, G. BOSE, S. CHANDRA, and D.K. SHARMA, "MEMS: Technology, Design, CAD and Applications," pp. 24-25, Jan. 2002. | |
| HR | 1 | S. CASS, "MEMS in Space," IEEE Spectrum, Vol. 38, Issue 7, pp. 56-61, July 2001. | |
| HR | 1 | D.C. HUTCHISON, K. OHARA, and A. TAKEDA, "Application of Second Generation Advanced Multimedia Display Processor (AMDP2) in a Digital Micro-Mirror Array Based HDTV," Int'l Conference on Consumer Electronics (ICCE) pp. 294-295, June 2001. | |
| HR | 1 | R.S. PAYNE, S. SHERMAN, S. LEWIS, and R.T. HOWE, "Surface Micromachining: From Vision to Reality to Vision," Proc. of International Solid State Circuits Conference, pp. 164-165, Feb. 1995. | |
| HR | 1 | R. OBOE, "Use of MEMS Based Accelerometers in Hard Disk Drives," Proc. of International Conference on Advanced Intelligent Mechatronics, Vol. 2, pp. 1142-1147, 2001. | |
| HR | 1 | A. HARTZELL and D. WOODILLA, "Reliability Methodology for Prediction of Micromachined Accelerometer Stiction," Proc. of Reliability Physics Symposium, pp. 202-205, March 1999. | |
| HR | 1 | N. DEB and R.D. (Shawn) BLANTON, "Analysis of Failure Sources in Surface-Micromachined MEMS," Proc. International Test Conference, pp. 739-749, Oct. 2000. | |
| HR | 1 | D. DE BRUYKER, A. COZMA, and R. PUERS, "A Combined Piezoresistive/Capacitive Pressure Sensor With Self-Test Function Based on Thermal Actuation," Proc. Solid State Sensors and Actuators, Vol. 2, pp. 1461-1464, 1997. | |
| HR | 1 | H.V. ALLEN, SC.C. TERRY, and D.W. DE BRUIN, "Self-Testable Accelerometer Systems," Proc. Micro Electro Mechanical Systems, pp. 113-115, 1989. | |

| | | | |
|--------------------|--------------|-----------------|--------|
| Examiner Signature | Helen Kwolek | Date Considered | 5/1/05 |
|--------------------|--------------|-----------------|--------|

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹ Applicant's unique citation designation number (optional). ² Applicant is to place a check mark here if English language Translation is attached. This collection of information is required by 37 CFR 1.98. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 2 hours to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

If you need assistance in completing the form, call 1-800-PTO-9199 (1-800-786-9199) and select option 2.



PTO/SB/088 (08-03)

Approved for use through 07/31/2006. OMB 0651-0031

U.S. Patent and Trademark Office; U.S. DEPARTMENT OF COMMERCE

Under the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it contains a valid OMB control number.

Substitute for form 1449/PTO

Complete if Known

**INFORMATION DISCLOSURE
STATEMENT BY APPLICANT**

(Use as many sheets as necessary)

Sheet

2

of

3

Application Number

10/666,147

Filing Date

18 September 2003

First Named Inventor

Deb et al.

Art Unit

2858

Examiner Name

Not Yet Assigned

Attorney Docket Number

DB001039-001

NON PATENT LITERATURE DOCUMENTS

| Examiner Initials* | Cite No. ¹ | Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published. | T ² |
|--------------------|-----------------------|---|----------------|
| HZ | 1 | B. CHARLOT, S. MIR, F. PARRAIN, and B. COURTOIS, "Electrically Induced Stimuli for MEMS Self-Test," Proc. VLSI Test Symposium, pp. 210-215, Apr.-May 2001. | |
| HZ | 2 | R. ROSING, A. LECHNER, A. RICHARDSON, and A. DOREY, "Fault Simulation and Modelling of Microelectromechanical Systems," Computing and Control Engineering Journal, Vol. 11, Issue 5, pp. 242-250, Oct. 2000. | |
| HZ | 3 | A. KOLPEKWAR, R.D. BLANTON, and D. WOODILLA, "Failure Modes for Stiction in Surface-Micromachined MEMS," Proc. of International Test Conference, pp. 551-556, Oct. 1998. | |
| HZ | 4 | T. JIANG and R.D. BLANTON, "Particulate Failures for Surface-Micromachined MEMS," Proc. of International Test Conference, pp. 329-337, Sept. 1999. | |
| HZ | 5 | H. LUO, G.K. FEDDER, and L.R. CARLEY, "A 1 mG CMOS-MEMS Accelerometer," Proc. of Micro Electro Mechanical Systems, PP. 502-507, Jan. 2000. | |
| HZ | 6 | W.C. TANG, T.-C.H. NGUYEN, M.W. JUDY, and R.T. HOWE, "Electrostatic Comb Drive of Lateral Polysilicon Resonators," Sensors and Actuators A, Vol. 21, Nos. 1-3, pp. 328-331, Feb. 1990. | |
| HZ | 7 | J. XUESONG, J.I. SEEGER, M. KRAFT, and B.E. BOSER, "A Monolithic Surface Micromachined Z-axis Gyroscope with Digital Output," Symposium on VLSI Circuits, pp. 16-19, 2000. | |
| HZ | 8 | N. DEB and R.D. BLANTON, "High-Level Fault Modeling in Surface-Micromachined MEMS," Proc. of Design, Test, Integration, and Packaging of MEMS/MOEMS, pp. 228-235, May 2000. | |
| HZ | 9 | J. WU, G.K. FEDDER, and L.R. CARLEY, "A Low-Noise Low-Offset Chopper-Stabilized Capacitive-readout Amplifier for CMOS MEMS Accelerometers," Proc. of International Solid State Circuits Conference, pp. 428-429, Feb. 2002. | |
| HZ | 10 | O. TABATA, K. TERASOMA, N. AGAWA, and K. YAMAMOTO, "Moving Mask LIGA (M/sup 2/LIGA) Process for Control of Side Wall Inclination," Proc. of Micro Electro Mechanical Systems Conference, pp. 252-256, Jan. 1999. | |

Examiner
Signature

Helen Kuroki

Date

Considered

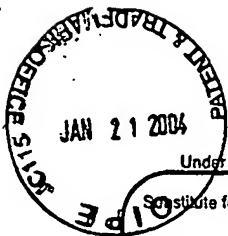
5/5/05

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

1 Applicant's unique citation designation number (optional). 2 Applicant is to place a check mark here if English language Translation is attached.

This collection of information is required by 37 CFR 1.98. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 2 hours to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

If you need assistance in completing the form, call 1-800-PTO-9199 (1-800-786-9199) and select option 2.



PTO/SB/08B (08-03)

Approved for use through 07/31/2006. OMB 0651-0031

U.S. Patent and Trademark Office; U.S. DEPARTMENT OF COMMERCE

Under the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it contains a valid OMB control number.

Substitute for form 1449/PTO

Complete if Known

INFORMATION DISCLOSURE
STATEMENT BY APPLICANT

(Use as many sheets as necessary)

Sheet 3

of 3

Application Number 10/666,147

Filing Date 18 September 2003

First Named Inventor Deb et al.

Art Unit 2858

Examiner Name Not Yet Assigned

Attorney Docket Number DB001039-001

NON PATENT LITERATURE DOCUMENTS

| Examiner Initials* | Cite No. ¹ | Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published. | T ² |
|--------------------|-----------------------|---|----------------|
| HK | | S.V. IYER, H. LAKDAWALA, G.K. FEDDER, and T. MUKHERJEE, "Macromodeling Temperature-Dependent Curl in CMOS Micromachined Beams," Proc. of Modeling and Simulation of Microsystems Conference, pp. 88-91, March 2001. | |
| HK | | Q. JING, H. LUO, T. MUKHERJEE, L.R. CARLEY, and G.K. FEDDER, "CMOS Micromechanical Bandpass Filter Design Using a Hierarchical MEMS Circuit Library," Proc. of Micro Electro Mechanical Systems Conference, pp. 187-192, Jan. 2000. | |
| HK | | D.A. KOESTER, R. MAHADEVAN, and K.W. MARKUS, MUMPS Introduction and Design Rules, MCNC MEMS Technology Applications Center, 3021 Cornwallis Road Research Triangle Park, NC, Oct. 1994. | |
| | | | |
| | | | |
| | | | |
| | | | |
| | | | |
| | | | |
| | | | |
| | | | |

| | | | |
|--------------------|------------|-----------------|--------|
| Examiner Signature | Helen Kwok | Date Considered | 5/5/05 |
|--------------------|------------|-----------------|--------|

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹ Applicant's unique citation designation number (optional). ² Applicant is to place a check mark here if English language Translation is attached.

This collection of information is required by 37 CFR 1.98. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 2 hours to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

If you need assistance in completing the form, call 1-800-PTO-9199 (1-800-786-9199) and select option 2.